

Photolithographically Fabricated Silicon Photonic Crystal Nanocavity Photoreceiver with a Laterally Integrated *pin* Diode

> Nurul Ashikin Binti Daud, Tomohiro Tetsumoto and Takasumi Tanabe

Department of Electronics and Electrical Engineering, Keio University

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1. Background

2. Device Design and Fabrication

Photolithographic fabrication

3. Photoreceiver properties

- Leak current
- Transmission and current spectrum at different input power
- Responsivity

4. Photoreceiver operation

• Time – domain measurement



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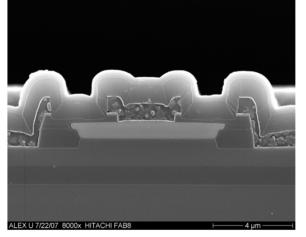
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Previous Research

1. Ge integration on Si detector



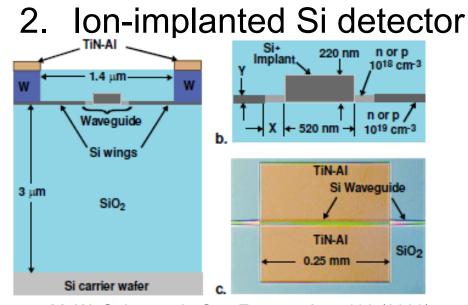
T. Yin, et. al., Opt. Express **15**, 13965 (2007)

□ <u>Advantages :</u>

- High speed (31 GHz)
- High sensitivity (QE~80%)
- Good responsivity (0.89 ~ 1.16 A/W)

☐ Disadvantages :

- Complicated in fabrication
- Large dark current due to defect (169 nA)



M. W. Geis, et. al., Opt. Express **17**, 5193 (2009)

□ Advantages :

- CMOS compatible (all-silicon)
- Good sensitivity and speed
- Good responsivity : 0.5 ~ 10 A/W)

□ Disadvantages :

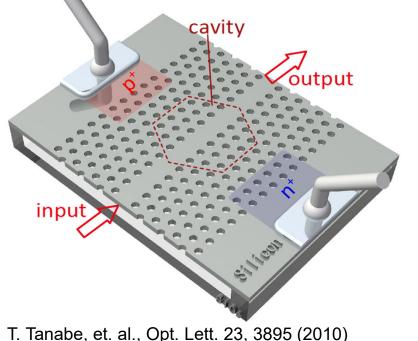
- Unstable (large aging effect)
- Large dark current due to defect (0.5 nA to 0.5 µA)

Background

All-Si Photoreceiver



Detect 1.5-µm telecom light using Si-chip integrated *p-i-n* diode



□<u>Advantages :</u>

- Low dark current
 - Because it is all-silicon
- High sensitivity
 - Due to high-Q cavity
- Requires low optical power

□<u>Disadvantages :</u>

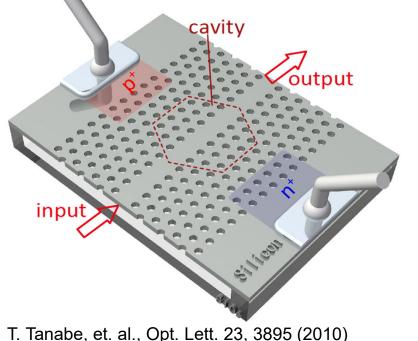
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 - Frangible and unstable
 - Incompatible with Si photonic devices
- Fabricated by EB lithography
 - High in accuracy but time consuming process

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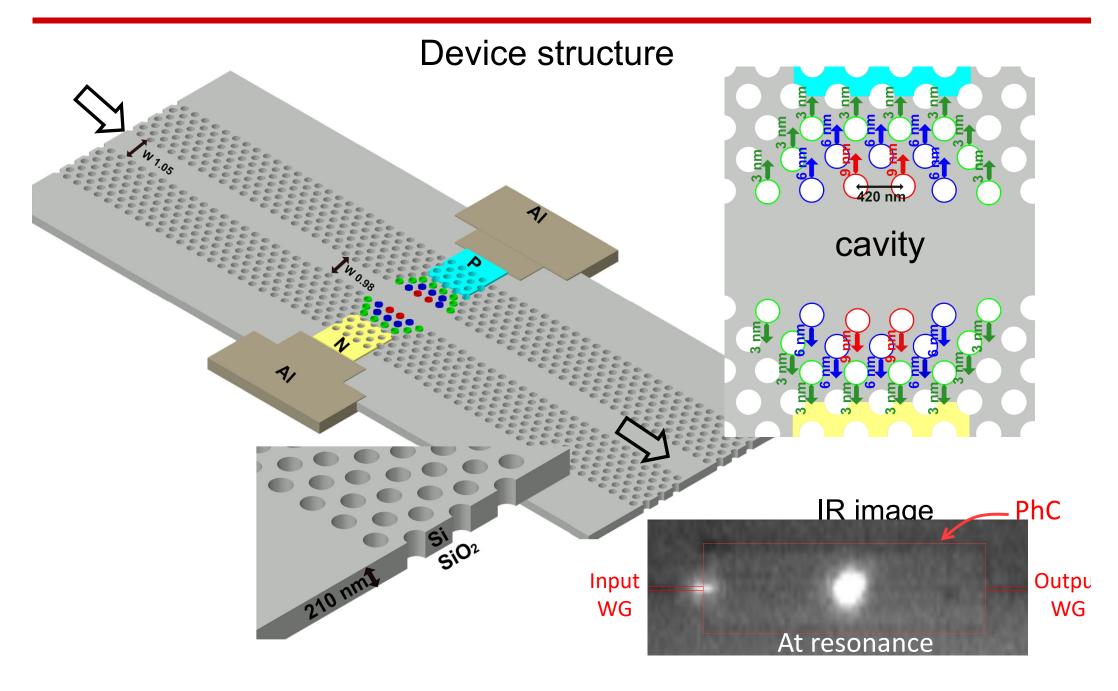
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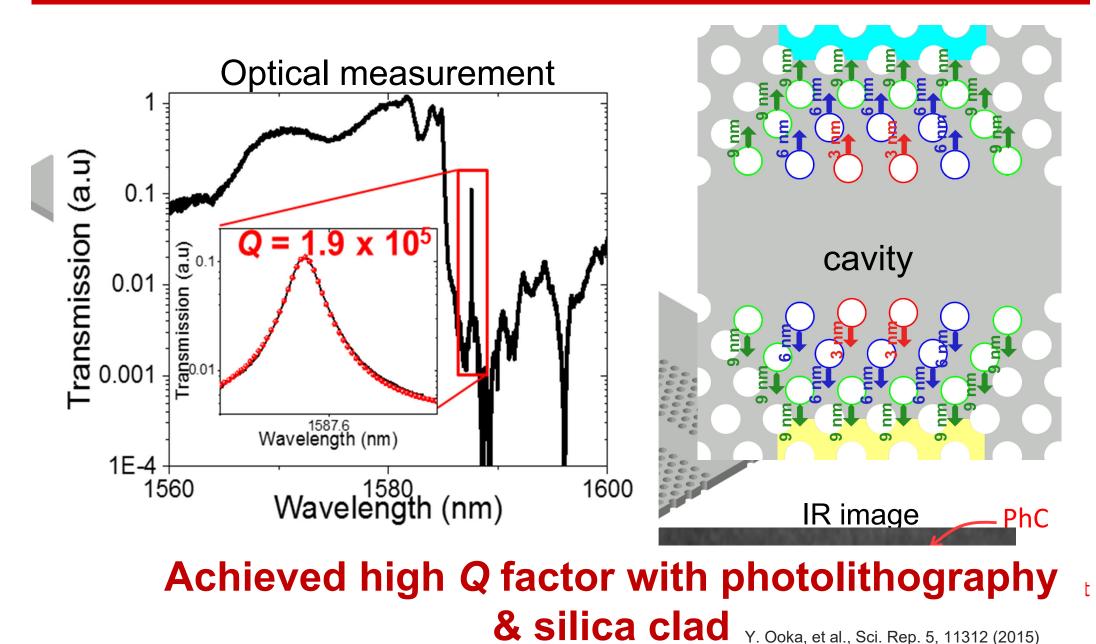
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PhC nanocavity photoreceiver w/ pin diode



PhC nanocavity photoreceiver w/ pin diode



1. Ouka, et al., Sul. Rep. 5, 11512



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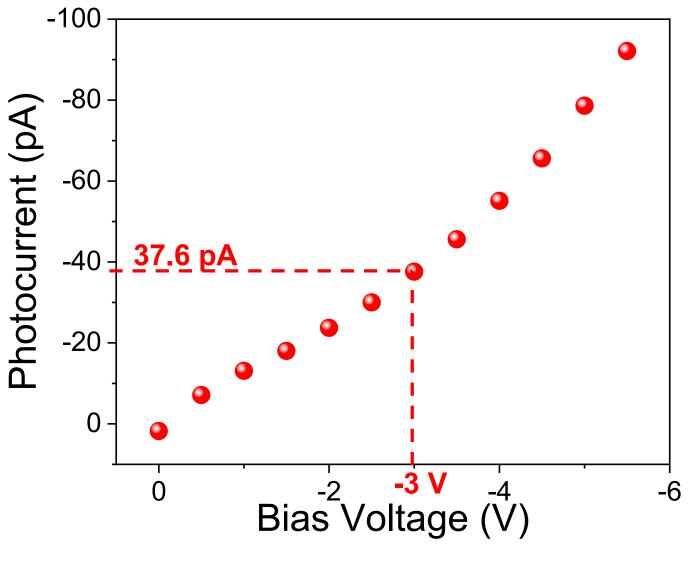
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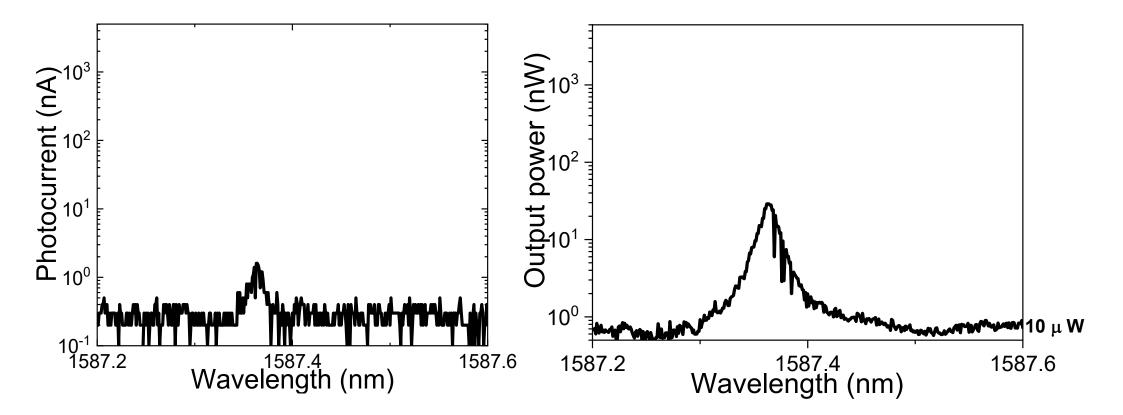
Dark (leak) current at RT



Value of leak current at -3 V is 37.6 pA

Photoreceiver properties

Transmission and current spectrum at different input power

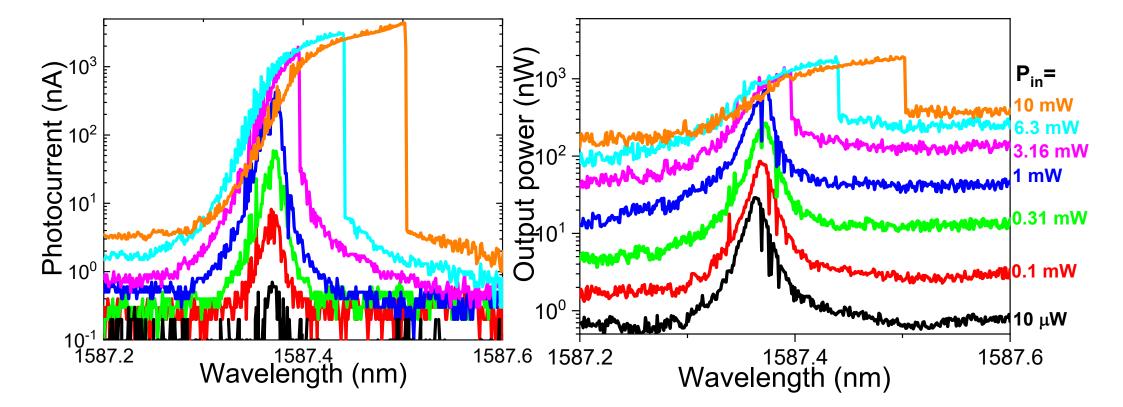


Resonance of cavity enhanced the photocurrent

Photoreceiver properties

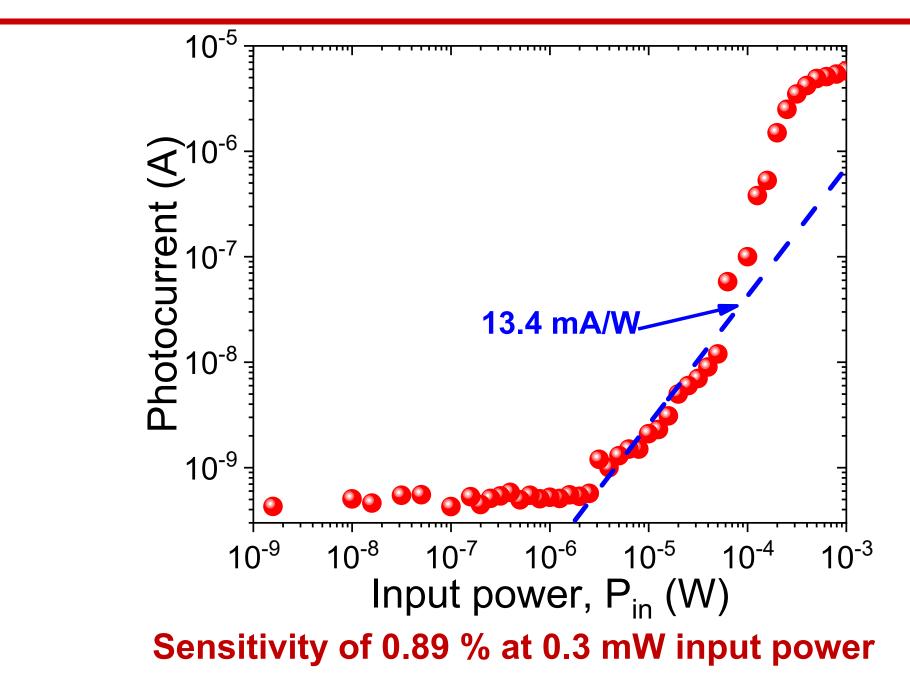
Transmission and current spectrum at different input power





Thermo-bistability effect where carriers are generated by the two-photon absorption (TPA)

Responsivity of the device





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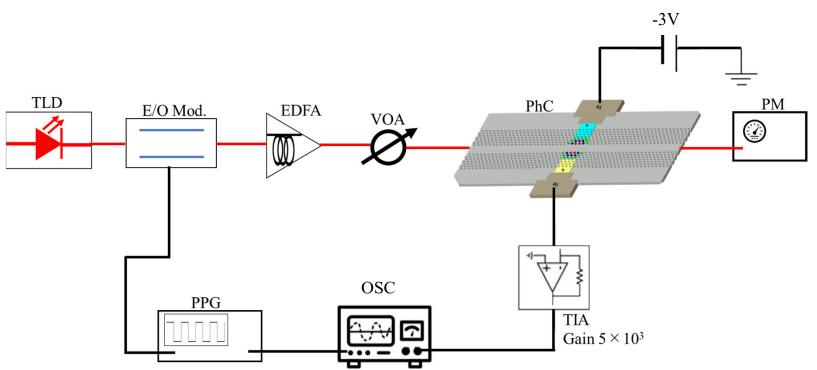
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Time-domain measurement

Experimental setup



TLD : Tunable Laser Diode

E/O Mod. : Electro-optic modulator

EDFA : Erbium doped frequency amplifier

VOA : Variable optical attenuator

PM : Power meter

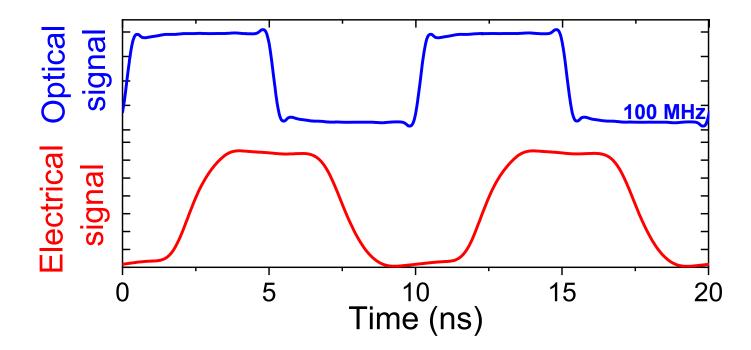
PPG : Pulse pattern generator

OSC : Oscilloscope

TIA : Trans-impedance amplifier

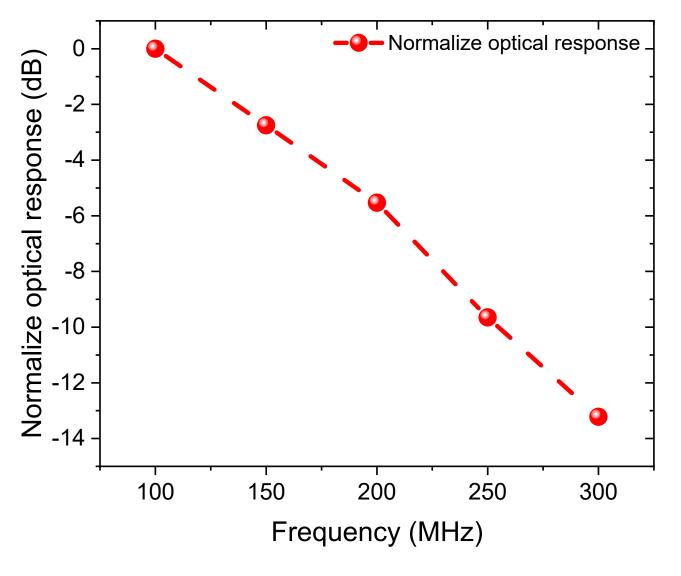
Time-domain measurement

Square pulse



0.1 GHz photoreceiver operation at the resonance cavity

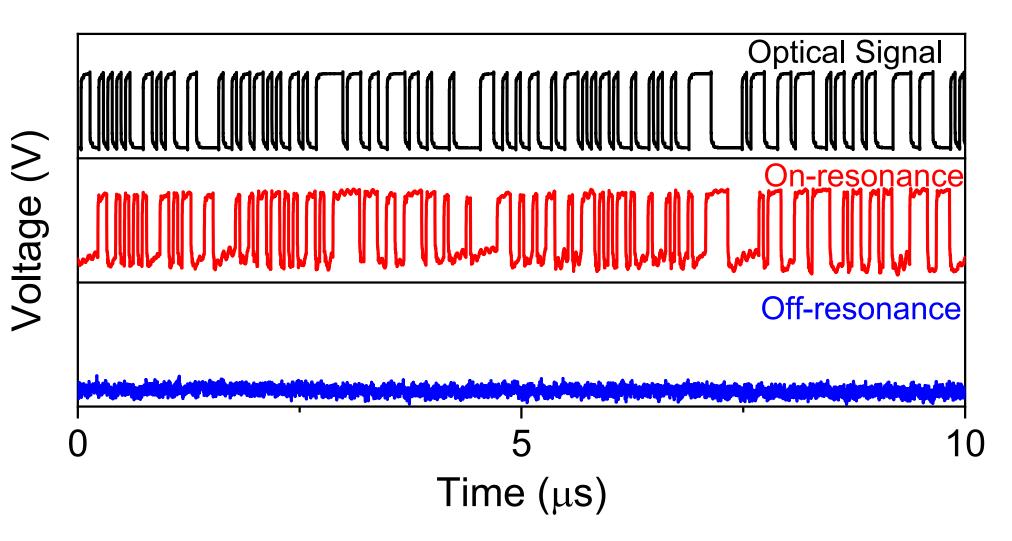
Time-domain measurement



-3 dB cut-off frequency shows at 0.15 GHz

0.1 Gb/s photoreceiver demonstration

Pseudo random bit sequence pulse





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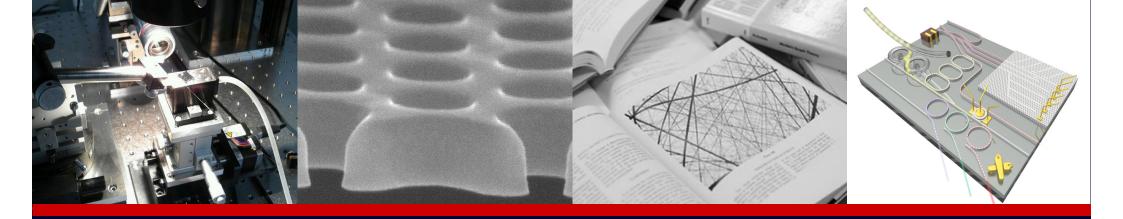
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Achievements of current work

	Quant. eff.	Dark current	Min. detectable in. light power	Device length	Operation voltage	Speed	Coupling w/ fiber	Referen
Si PhC (SiO ₂ clad)	0.89%	37.6 pA	~100 nW	8.4 μm	-3V	0.1 GHz	-1.6 dB	This wc (2018
Si PhC (AB)	9.7%	15 pA	0.9 nW	8.4 μm	-3 V	0.1 GHz	-12 dB	APL 9(10110 (2010)
Ge on Si	71%	169 nA	~190 nW	50 μm	-2 V	31 GHz	NA	OE 15 13965 (2007)
Si⁺ mplanted Si	~16%	0.5 nA	~2.5 nW	3~4 mm	-5 V	0.2 GHz	NA	IEEE-P 18, 188 (2006



Thank you

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> Electronics and Electrical Engineering, Keio University, Japan *ashikin@phot.elec.keio.ac.jp

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